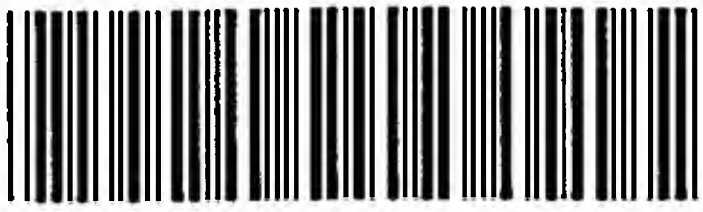


Search Notes 	Application No.	Applicant(s)	
	10/605,326	YEH ET AL.	
	Examiner	Art Unit	
	Stephen W. Smoot	2813	

SEARCHED			
Class	Subclass	Date	Examiner
438	525	8/21/2004	SWS
438	528	8/21/2004	SWS
438	586	8/21/2004	SWS
438	592	8/21/2004	SWS
438	595	8/21/2004	SWS
438	637	8/21/2004	SWS
438	675	8/21/2004	SWS
438	766	8/21/2004	SWS
438	770	8/21/2004	SWS
Updated	Above	2/2/2005	SWS
Updated	Above	4/6/2005	SWS

INTERFERENCE SEARCHED			
Class	Subclass	Date	Examiner
Same as Above		4/6/2005	SWS

SEARCH NOTES (INCLUDING SEARCH STRATEGY)		
	DATE	EXMR
Key Words: Ion Implantation - Tilt, Sidewall; Thermal Oxidation; Rapid Thermal Process;	8/21/2004	SWS
Self-Aligned Contact (SAC); Plug; Contact Opening, Contact Hole, Conductive Via; Gate, Source, Drain.	8/21/2004	SWS
Updated Above Search	2/2/2005	SWS
Implantation - Nitrogen, Oxygen, Argon; Field Effect Transistors.	2/2/2005	SWS
Updated Above Searches	4/6/2005	SWS
Search Tools - EAST (attached): USPAT; US PG PUBS; Derwent; EPO; JPO; IBM TDB	8/21/2004; 2-2-05; 4-6-05	SWS